

IN THE CLAIMS:

Please cancel claims 1-5 and 21, add new claim 53, and amend the claims as follows:

1.-5. (Cancelled)

6. (Currently Amended) A method for testing of a substrate with several test objects with a test apparatus having a holder for the substrate, a displacement unit for the holder with a holder displacement range in x-direction and a holder displacement range in y-direction, and a contact unit for contacting of the at least one test object, whereby the contact unit has a displacement range in x-direction and/or in y-direction, and the contact unit displacement range in x-direction and/or the contact unit displacement range in y-direction are smaller than the respective holder displacement range, comprising the following steps:

[[ - ]] putting the substrate on [[a]] the holder;

[[ - ]] contacting of a first test object with [[a]] the contact unit, wherein the contact unit has essentially maximal the dimension of half of the holder dimension in one direction perpendicular to the optical axis;

[[ - ]] positioning of the substrate so that a first area of the first test object lies in a test range of the test apparatus;

[[ - ]] testing of the first area of the test object;

[[ - ]] displacing the substrate so that at least a further area of the first test object lies in the test range of the test apparatus;

[[ - ]] displacing the contact unit so that the position of the contact unit is essentially unchanged with respect to the first test object;

[[ - ]] testing of the further area of the test object; and

[[ -]] displacing the contact unit and the substrate relative to each other so that a further test object can be contacted.

7. (Previously presented) The method of claim 6, wherein the contact unit is displaced by tracking.

8. (Previously presented) The method of claim 6, wherein the contact unit is displaced by carrying along.

9. (Previously presented) The method of claim 6, wherein the contact unit is displaced as long as a contact to the substrate is present.

10. (Previously presented) The method of claim 6, wherein the test range is scanned by a beam deflection of a corpuscular beam in two directions.

11. (Previously presented) The method of claim 6, wherein the test range is scanned by a beam deflection of a corpuscular beam in one direction and a substrate movement in another direction.

12. (Previously presented) The method of claim 6, wherein the contact unit is displaced as long as no contact to the substrate is present.

13. (Previously presented) The method of claim 6, wherein the contact unit is adapted to different forms of test objects.

14. (Previously presented) The method of claim 6, wherein the testing is conducted by scanning of the test range with a corpuscular beam and measurement of the second area electrons.

15. (Previously presented) The method of claim 6, wherein the testing is conducted by scanning of the test range with a corpuscular beam and measurement of a signal fed through the contact unit.

16. (Previously presented) The method of claim 6, wherein before the testing a vacuum of smaller than  $1 \cdot 10^{-3}$  mbar is generated.

17. (Currently Amended) An apparatus for contacting for the test of at least one test object on a substrate, comprising:

[[ - ]] a holder for the substrate;

[[ - ]] displacement unit for the holder with a holder displacement range in x-direction and a holder displacement range in y-direction;

[[ - ]] a contact unit for contacting of the at least one test object, whereby the contact unit has a displacement range ~~is displaceable~~ in x-direction and and/or in y-direction, and the contact unit displacement range in x-direction and/or the contact unit displacement range in y-direction are smaller than the respective holder displacement range.

18. (Previously presented) The apparatus of claim 17, wherein the contact unit displacement range in x-direction and in y-direction is larger than a corresponding contact alignment displacement range of the contact unit.

19. (Currently Amended) An apparatus for contacting for the test of at least one test object on the substrate, whereby for the test a test apparatus with an optical axis is used, comprising:

[[ - ]] a holder for a substrate with at least one test object;

[[ - ]] a displacing unit for the holder;

[[ - ]] a contact unit for contacting of the at least one test object, whereby the contact unit is displaceable and has essentially maximal the dimension of half of the holder dimension in one direction perpendicular to the optical axis.

20. (Previously presented) The apparatus of claim 19, wherein the contact unit has essentially maximal the dimensions of half of the holder the dimensions in two directions perpendicular to the optical axis.

21. (Cancelled)

22. (Currently Amended) The apparatus of claim 17, wherein the contact unit is displaceable by ~~at least 5 cm, preferably by~~ at least 20 cm.

23. (Previously presented) The apparatus of claim 17, wherein the contact unit has dimensions, so that no area to be tested of the test object to be tested is covered by the contact unit.

24. (Previously presented) The apparatus of claim 17, wherein the contact unit has a size which is larger than the test range during testing.

25. (Previously presented) The apparatus of claim 17, wherein the contact unit is connected with a displacing unit with a drive for displacement relative to the optical axis.

26. (Previously presented) The apparatus of claim 17, wherein a synchronization unit exists, which synchronizes the displacing unit of the contact unit and of the holder.
27. (Previously presented) The apparatus of claim 17, wherein the contact unit has contact pins for contacting.
28. (Previously presented) The apparatus of claim 27, wherein the contact pins for contacting with the contact unit are not movable relative to each other during the testing of a substrate.
29. (Previously presented) The apparatus of claim 27, wherein the contact pins for contacting with the contact unit are not movable relative to each other.
30. (Previously presented) The apparatus of claim 17, wherein the contact unit is adjustable on different sizes of test objects.
31. (Previously presented) The apparatus of claim 17, wherein the test object is at least one display with a contact assembly.
32. (Previously presented) The apparatus of claim 17, wherein the apparatus is adapted to be used in a vacuum.
33. (Previously presented) The apparatus of claim 17, wherein the contact unit is connected with an external control and/or a measurement unit.

34. (Previously presented) The apparatus of claim 17, wherein the contact unit is displaceable during the testing of the substrate.

35. (Currently Amended) The [[A]] test system of claim 17, further comprising:  
an evacuable test chamber; and  
a corpuscular beam column with an optical axis; ~~and~~  
~~an apparatus for contacting for the test of at least one test object on a substrate.~~

36. (Currently Amended) A method for testing of a substrate with several test ~~object~~ objects, wherein ~~for testing~~ a test apparatus with an optical axis is used for testing, comprising the following steps:

- [[ - ]] putting the substrate in a holder;
- [[ - ]] contacting of a first test object with a contact unit;
- [[ - ]] positioning of the substrate and the optical axis relative to each other so that a first area of the first test object lies in a test range of the test apparatus.
- [[ - ]] testing of the first area of the test object;
- [[ - ]] displacing the substrate and the optical axis relative to each other so that at least a further area of the first test object lies in the test range of the test apparatus;
- [[ - ]] testing of the further area of the test object;
- [[ - ]] displacing the contact unit and the substrate relative to each other, so that a further test object can be contacted.

37. (Previously presented) The method of claim 36, wherein the optical axis of the test apparatus is positioned relative to the substrate and the contact unit is displaced relative to substrate.

38. (Previously presented) The method of claim 36, wherein the test range is detected with a light optical system.

39. (Previously presented) The method of claim 36, wherein the contact unit is adapted to different forms of the test objects.

40. (Currently Amended) An apparatus for contacting for the test of at least one test object on ~~[[the]]~~ a substrate, whereby for the test a test apparatus with an optical axis is used, comprising:

[[ - ]] a holder for substrate with at least one test object;

[[ - ]] a displacing unit for displacement of the optical axis;

[[ - ]] a contact unit for contacting of the at least one test object, whereby the contact unit is displaceable relative to the optical axis and independent thereof relative to the holder and has essentially maximal the dimension of a half of the holder dimension in one direction perpendicular to an optical axis.

41. (Previously presented) The apparatus of claim 40, wherein the contact unit has essentially maximal the dimension of half of the holder dimension in two directions perpendicular to an optical axis.

42. (Currently Amended) An apparatus for contacting for the test of at least one test object on the substrate, whereby for the test a test apparatus with an optical axis is used, comprising:

[[ - ]] an optical axis displaceable with respect to the holder for the substrate;  
and

[[ -]] a displaceable contact unit, whereby the contact unit is displaceable during the testing of the substrate with respect to the optical axis and with respect to the holder.

43. (Currently Amended) The apparatus of claim 40, wherein the contact unit is displaceable by ~~at least 50 mm, preferably by~~ at least 200 mm.

44. (Previously presented) The apparatus of claim 40, wherein the contact unit has dimensions so that no area to be tested of the test object is covered by the contact unit.

45. (Previously presented) The apparatus of claim 40, wherein the contact unit has a size larger than the test range during testing.

46. (Previously presented) The apparatus of claim 40, wherein the contact unit is connected with a displacing unit with a drive for displacement relative to the optical axis.

47. (Previously presented) The apparatus of claim 40, wherein a synchronizing unit exists, which synchronizes the displacing unit of the contact unit and a further displacing unit.

48. (Previously presented) The apparatus of claim 47, wherein the further displacing unit is a displacing unit for the optical axis.

49. (Previously presented) The apparatus of claim 40, wherein the contact unit has contact pins for contacting.



50. (Previously presented) The apparatus of claim 40, wherein the contact unit is adaptable to different sizes of test objects.

51. (Previously presented) The apparatus of claim 40, wherein the test object is at least one display with a contact arrangement.

52. (Previously presented) The apparatus of claim 40, wherein the contact unit is connected with an external control and/or a measurement unit.

53. (New) A test system comprising:  
an apparatus for contacting for the test of at least one test object on a substrate, whereby for the test a test apparatus with an optical axis is used, comprising:  
a holder for the substrate with at least one test object;  
a displacing unit for displacement of the optical axis;  
a contact unit for contacting of the at least one test object, wherein the contact unit is displaceable relative to the optical axis and independent thereof relative to the holder and has essentially maximal the dimension of a half of the holder dimension in one direction perpendicular to an optical axis.